

What Is Claimed Is:

1. A micromechanical component, comprising:
a substrate; and ✓
a diaphragm positioned on the substrate; and
a region arranged underneath the diaphragm and made of a porous material, the region mechanically supporting and thermally insulating the diaphragm.
2. The micromechanical component according to claim 1, wherein:
the porous material is formed from a material of the substrate.
3. The micromechanical component according to claim 1, wherein:
a hollow space is formed underneath the region.
4. ✓ The micromechanical component according to claim 1, wherein:
the diaphragm layer is formed by oxidizing a surface of the substrate and a surface of the region.
5. The micromechanical component according to claim 1, wherein:
the region is completely oxidized.
6. ✓ The micromechanical component according to claim 1, further comprising:
a dew point sensor, including:
a thermocouple for measuring a temperature and arranged above the region,
an interdigital capacitor made of the porous material and arranged above the region,
a Peltier element device including at least one Peltier element for heating and cooling the diaphragm, and
a dew point measuring device for measuring a dew point with the aid of one of the following:
a mirror for optical evaluation, and
a capacitance of the interdigital capacitor and a temperature measured by the thermocouple.

7. The micromechanical component according to claim 1, further comprising:
a heat radiation sensor including:
an absorption device for absorbing a heat radiation provided above the region,
a Peltier element device including at least one Peltier element for generating a thermoelectric voltage corresponding to a temperature difference between a diaphragm region next to the region and a diaphragm region above the region, and
a temperature measuring device for measuring a temperature in the diaphragm region above the region.

8. The micromechanical component according to claim 7, wherein:
the temperature measuring device measures the temperature in the diaphragm region above the region based upon a thermoelectric voltage.

9. The micromechanical component according to claim 7, further comprising:
a control device that operates the Peltier element device to control the temperature in the diaphragm region above the region, wherein:
the temperature measuring device measures the temperature in the diaphragm region above the region based on a regulated output.

10. A method for manufacturing a micromechanical component including a substrate and a diaphragm positioned on the substrate, comprising the step of:
providing at least temporarily a region made of a porous material underneath the diaphragm in order to mechanically support and thermally insulate the diaphragm.

11. The method according to claim 10, further comprising the step of:
removing the region again after a formation of the diaphragm.